

**AMENDMENTS TO THE SPECIFICATION:**

On page 8, please replace lines 15-19 with the following:

Figure 5 is a flow chart illustrating an alternate lighting method according to the present invention; and

Figure 6 is an illustration of an alternative embodiment of the present invention[.] ; and

Figure 7 is an illustration of an alternative embodiment of the present invention.

On page 15, please replace lines 1-22 with the following:

Alternately, Figure 5 describes an extension of the basic method 200 wherein a second illuminator (65', Figure 7) is used in sequential fashion with the first illuminator 65 (also shown in Figure 7) method (202). In method 202, the second or alternate illuminator 65' is configured having a complementary intense light 91/lighting void 92 pattern as  
5 compared to the original 5 patterned illuminator 65. As defined, the additional steps outlined as 220, 225, and 230, performed after steps 205, 210, and 215, effect complete coverage of the parts surface 50 using preferential dark field illumination.

In this regard, after steps 205, 210 and 215 are completed, the part under inspection is positioned at a second location wherein the illumination fields of an  
10 illuminator 65' are selectively activated in an alternating on/off manner to produce an engineered illumination pattern such that an inverse engineered illumination pattern is enacted upon the surfaces of the part (step 220). This illuminator 65' is preferably a separate, alternate illuminator. The part under inspection is then illuminated using the inverse engineered illumination pattern produced by the alternate, patterned 15  
15 illuminator (step 225). Last, the light generated by the patterned illuminator that has subsequently reflected or scattered off the part under inspection is made available for the purpose of deducing quality status information related to the part (step 230). As with the method 200, the light generated by the patterned illuminator that reflected or scattered off the part under inspection is captured by, for example, the camera. The processor then  
20 analyzes the information that is captured for the purpose of deducing quality status information related to the part. As indicated above, a summary report may then be produced.